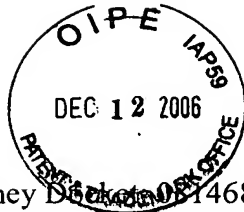


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Attorney Docket No. 1468-0307473
Client Reference: P-1795.000-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
BANINE ET AL.

Confirmation Number: 2813

Application No.: 10/748,851

Group Art Unit: 2851

Filed: December 31, 2003

Examiner: Della J. Rutledge

Title: LITHOGRAPHIC APPARATUS HAVING A DEBRIS-MITIGATION SYSTEM, A
SOURCE FOR PRODUCING EUV RADIATION HAVING A DEBRIS MITIGATION
SYSTEM AND A METHOD FOR MITIGATING DEBRIS

AMENDMENT

United States Patent and Trademark Office
Customer Service Window
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

In response to the Office Action dated September 12, 2006, please amend the above-
identified application as follows:

12/12/2006 RECEIVED 12/12/2006 02:23:15 10748851
BY 1011202 283.02 BA